

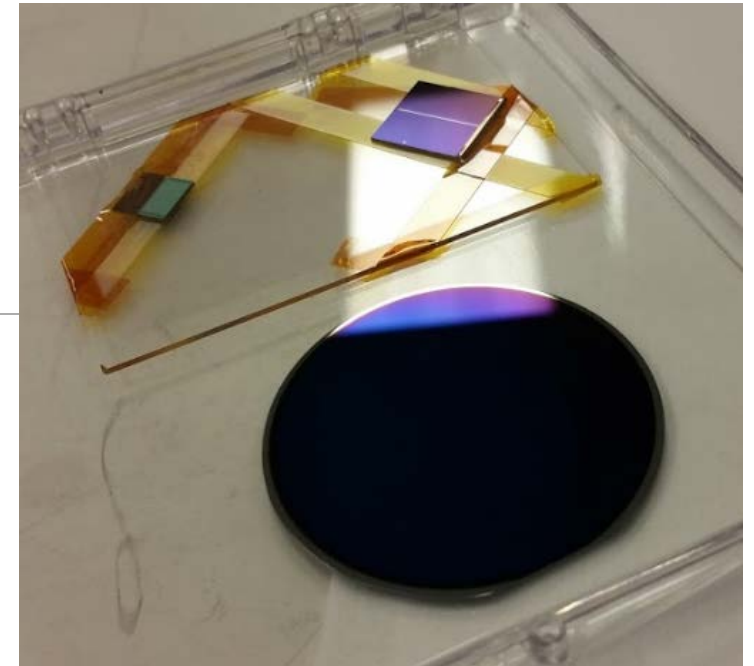
# 35<sup>th</sup> Annual Microelectronic Engineering Conference 2017:

## *MgF<sub>2</sub>-Ta<sub>2</sub>O<sub>5</sub> Anti Reflective Coating for 3<sup>rd</sup> Generation Solar Cells*

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05/09/2017



# Project Scope

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1. Develop a mathematical model to optimize  $\text{MgF}_2$ - $\text{Ta}_2\text{O}_5$  bi-layer anti-reflective coatings (ARCs).
2. Deposit the ARC on silicon substrates and test broad band reflectivity.
3. Measure the diffuse field reflectance of ARC.
4. Show an improvement in solar cell performance for a solar cell with the ARC verses without.

# Theory behind the Simulation Model

The method of resultant waves was applied in MATLAB to make iterative calculations in order to determine the film thickness combinations that result in the lowest average reflectivity.

## Boundary Conditions

$$r_{i-1} = \frac{n_{i-1} - n_i}{n_{i-1} + n_i} \quad t_{i-1} = 1 - r_{i-1} \quad \delta_i = \frac{2\pi d_i n_i}{\lambda} \quad E_+^i = \frac{E_+^{i+1} + r_i E_-^{i+1}}{t_i} \quad E_-^i = \frac{r_i E_+^{i+1} + E_-^{i+1}}{t_i} \quad n_0 | n_1 | n_2 | n_g = n_{air} | n(\lambda)_{MgF_2} | n(\lambda)_{Ta_2O_5} | n(\lambda)_{Si}$$

## Electric Field for m Dielectric Films

$$I_i = \begin{bmatrix} \frac{1}{t_i} & \frac{r_i}{t_i} \\ \frac{r_i}{t_i} & \frac{1}{t_i} \end{bmatrix} \quad T_i = \begin{bmatrix} e^{i\delta_i} & 0 \\ 0 & e^{-i\delta_i} \end{bmatrix} \quad M = I_0 \times T_1 \times I_1 \times T_2 \times \dots \times I_{m-1} \times T_m \times I_m \quad \begin{pmatrix} E_+^0 \\ E_-^0 \end{pmatrix} = M \begin{pmatrix} E_+^f \\ E_-^f \end{pmatrix} \quad \begin{pmatrix} E_+^f \\ E_-^f \end{pmatrix} = \begin{pmatrix} 1 \\ 0 \end{pmatrix}$$

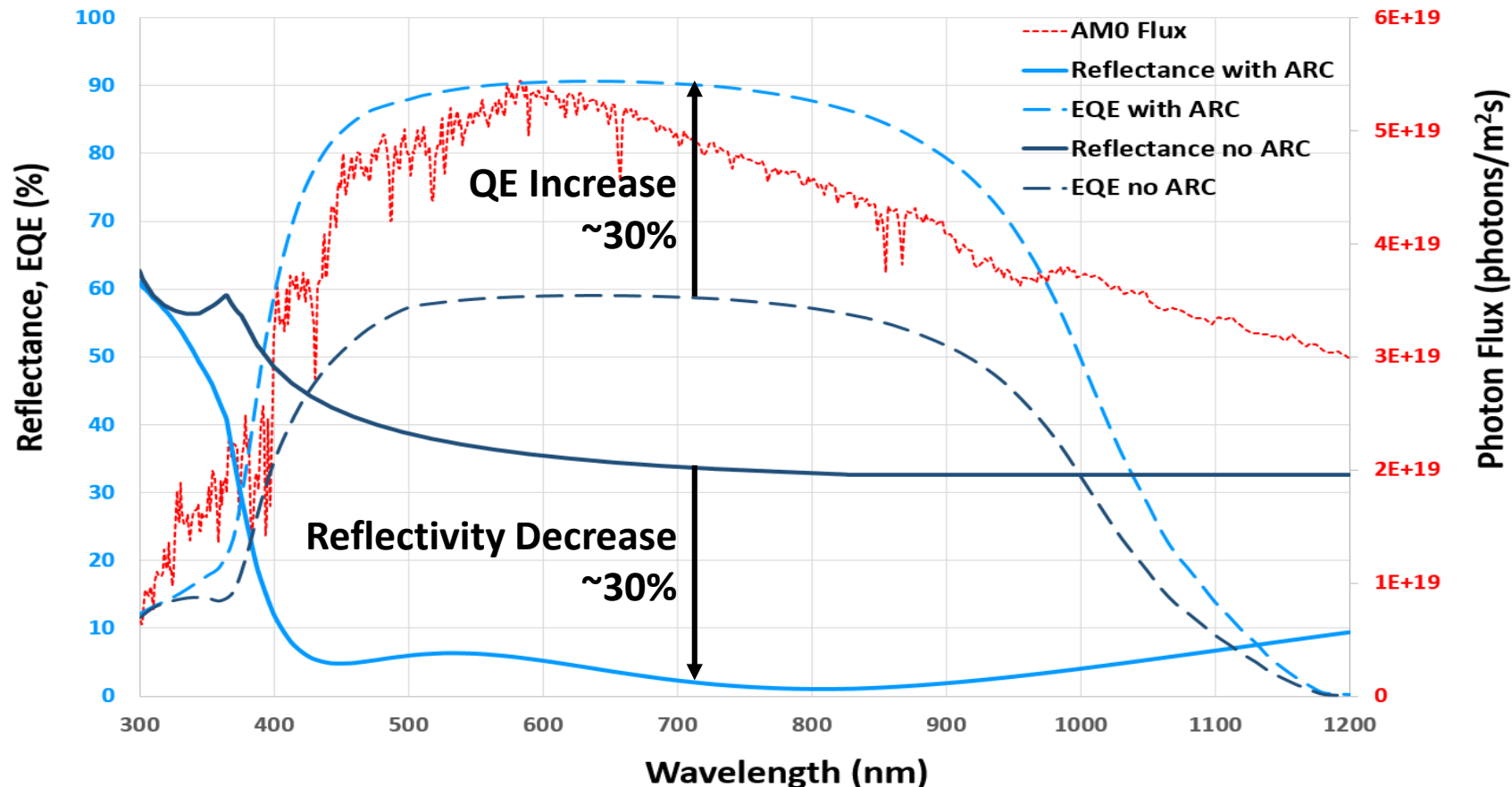
## Average Broad Band Reflectivity

$$\rho = \frac{E_-^0}{E_+^0} \quad R(\lambda) = |\rho| |\rho^*| \quad AM0 \text{ Flux} = F(\lambda) \quad R_e = \frac{\int_{\lambda_1}^{\lambda_2} F(\lambda) R(\lambda) d\lambda}{\int_{\lambda_1}^{\lambda_2} F(\lambda) d\lambda}$$

$\lambda$  – wavelength  
 $n$  – Complex index of refraction as a function of  $\lambda$   
 $r$  – Reflectance Fresnel coefficient  
 $t$  – Transmission Fresnel coefficient  
 $\delta$  – Change in phase of light through a medium  
 $d$  – Stack layer thickness  
 $E^+$  – Transmitted component of the light's electric field  
 $E^-$  – Reflected component of the light's electric field  
 $\rho$  – Stack reflectance coefficient  
 $R_e$  – Average stack reflectivity for a range of  $\lambda$

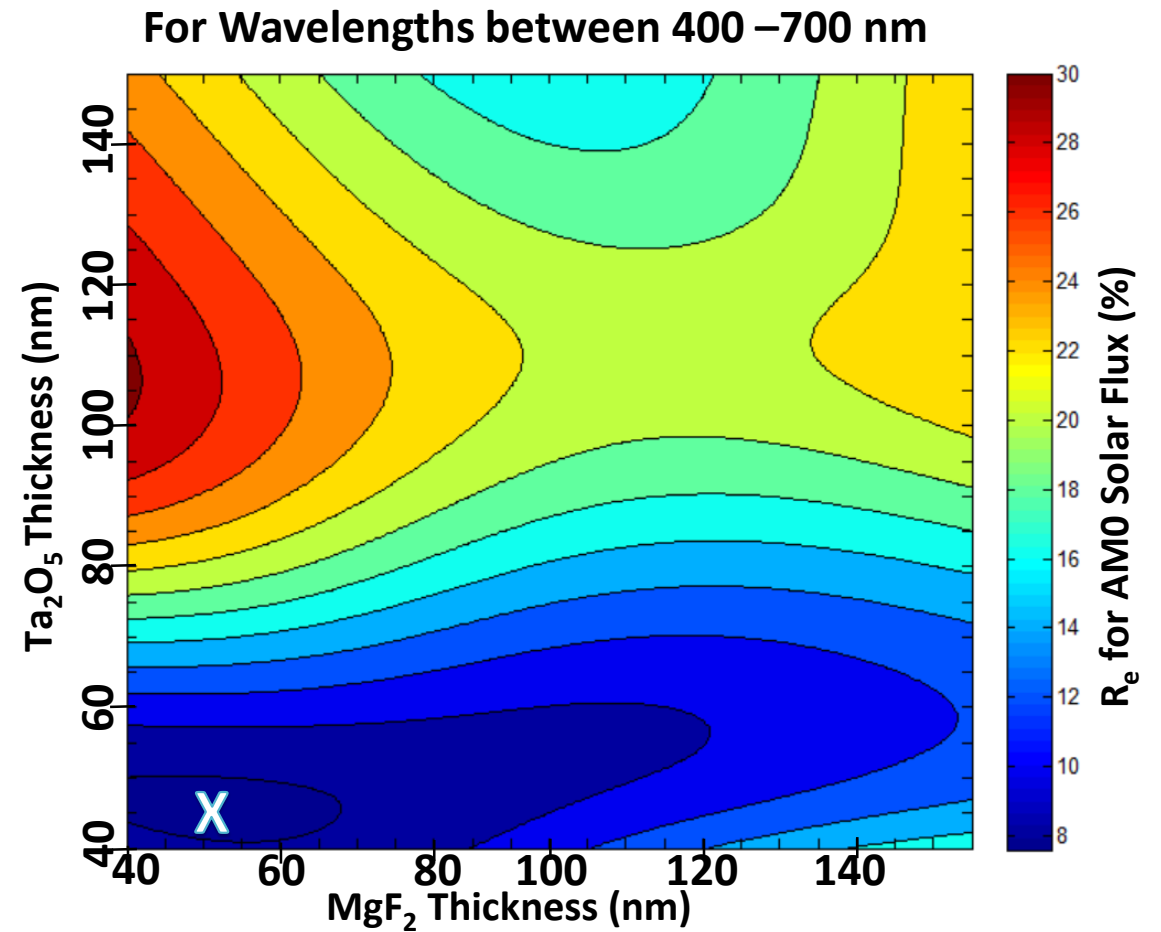
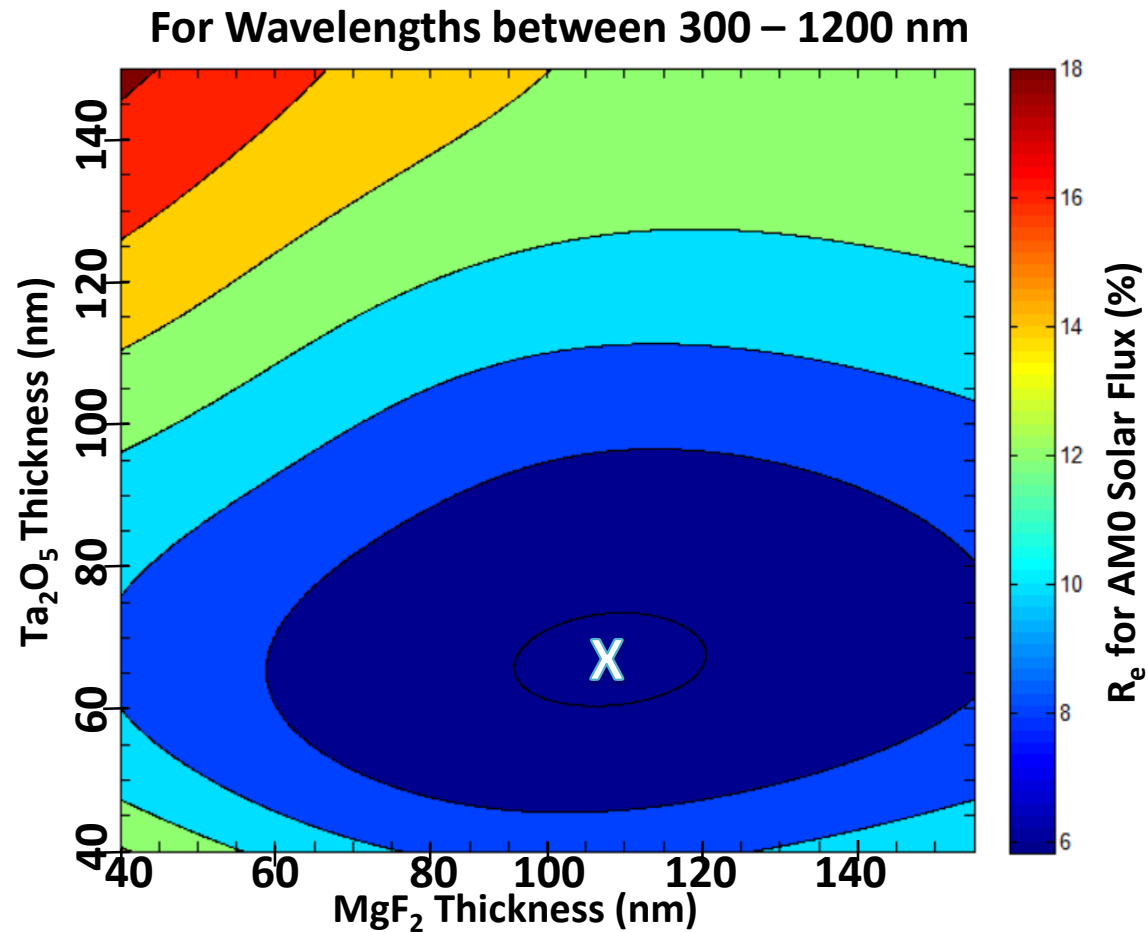
# Reflectivity and Quantum Efficiency Curves

Simulated Broad Band Reflectance and External Quantum Efficiency



- ❖ AM0 flux data is referenced from NREL
- ❖ Reflectivity curves were generated in MATLAB
- ❖ EQE curves were generated in PC1D where the simulated reflectivity data was imported.

# MgF<sub>2</sub>-Ta<sub>2</sub>O<sub>5</sub> Bi-layer Broad Band Reflectance Contour Plots



# ARC Deposition Process

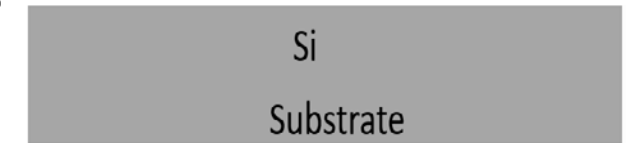
## (1) Ta<sub>2</sub>O<sub>5</sub> Reactive Sputter in CVC601

- 4" Tantalum target
- Base Pressure 5 mTorr
- 33% O<sub>2</sub> to Ar gas mixture
- 400W DC Power during deposition
- Deposition rate ~6 Å/s
- 117 second DC sputter
- Target thickness 70 nm

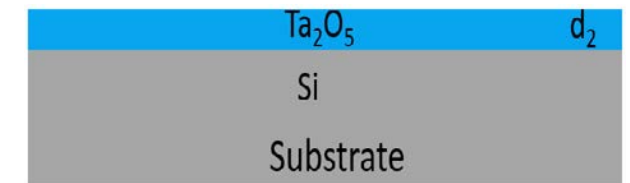
## (2) MgF<sub>2</sub> Thermal Evaporation in PVD75A

- MgF<sub>2</sub> crystals loaded in Mo boat
- Followed Brittany Smith's process
- Spacers added under samples to minimize the effect of bloom adding to thickness non uniformity
- Deposition rate ~3-4 Å/s at 95% source power
- Target thickness 105 nm or 0.105 kÅ
- Reflectometry (Filmetrics Reflectometer) technique was used on a glass monitor slide to confirm thicknesses

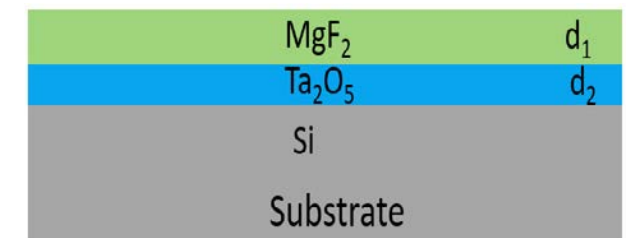
Start



(1)



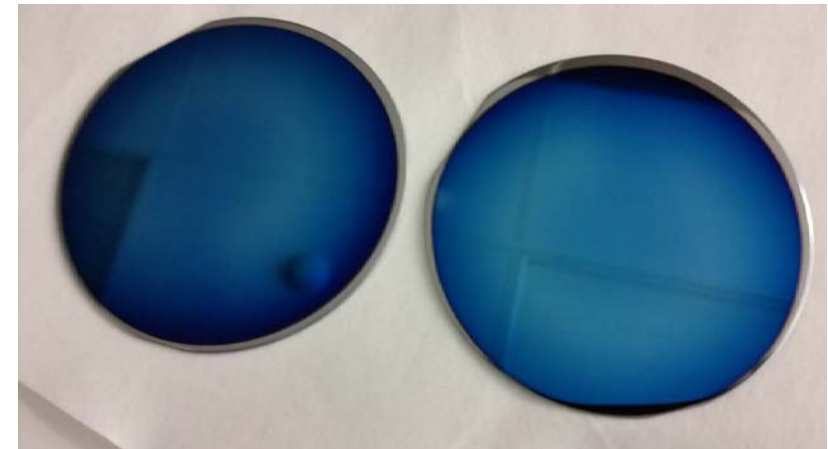
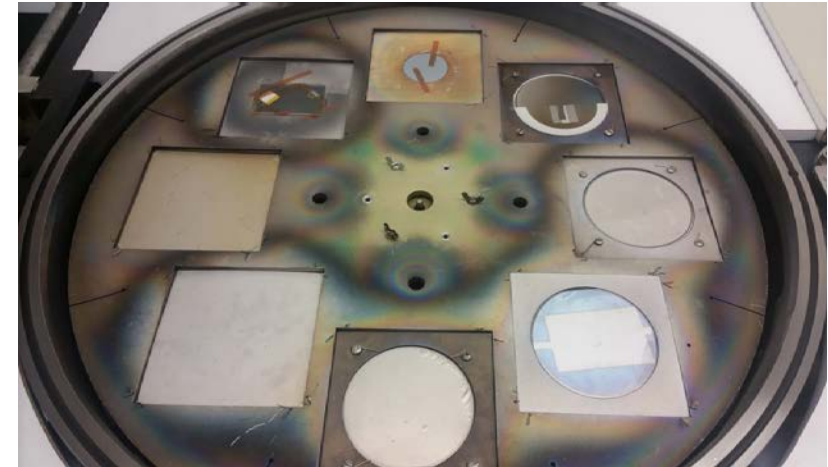
(2)



End

# Tantalum Oxide Reactive Sputter Findings

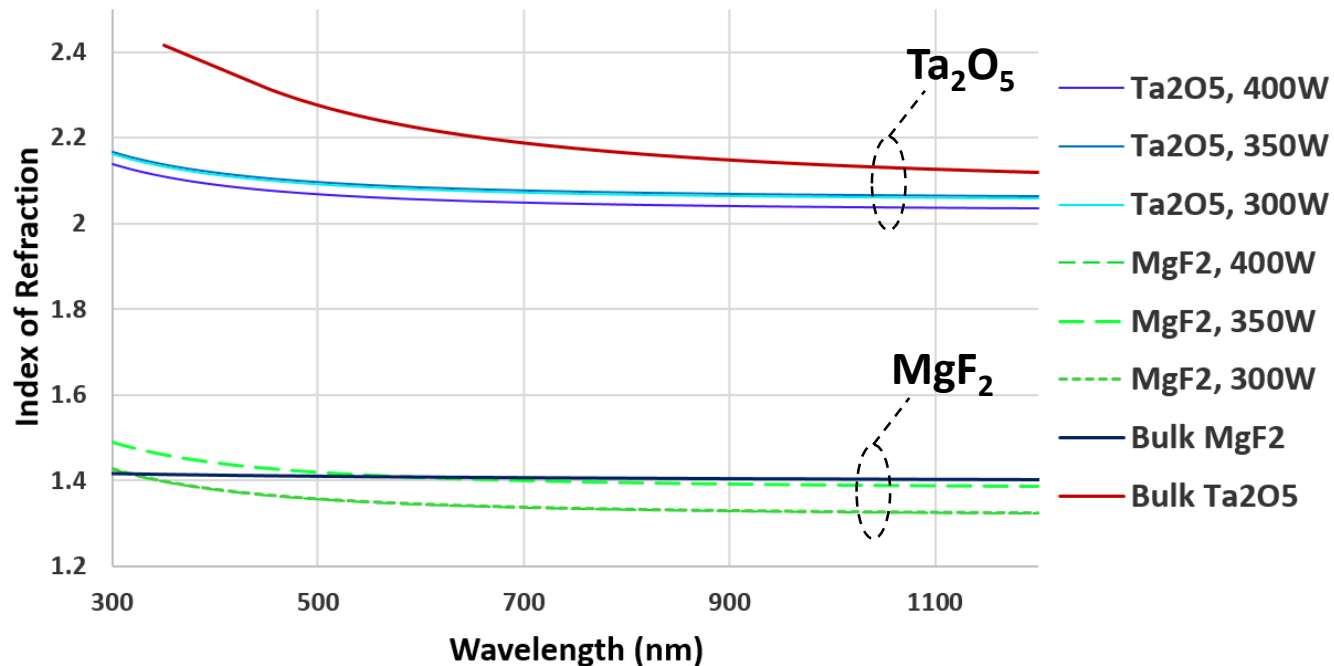
- ❖ DC sputter power 400W
  - ❖ Fastest deposition rate ( $\sim 6 \text{ \AA/s}$ )
  - ❖ No sacrifice in index of refraction
  - ❖ Thickness uniformity showed negligible change
- ❖ Flow rates set to  $9.3 \pm 0.2 \text{ sccm}$ 
  - ❖ Replaces oxygen consumed during deposition
  - ❖ Resulted in less change in chamber pressure during deposition
- ❖ 33% Oxygen/Argon gas mixture
  - ❖ Results in higher oxygen content in the film
  - ❖ Lower oxygen content results in more absorbing film



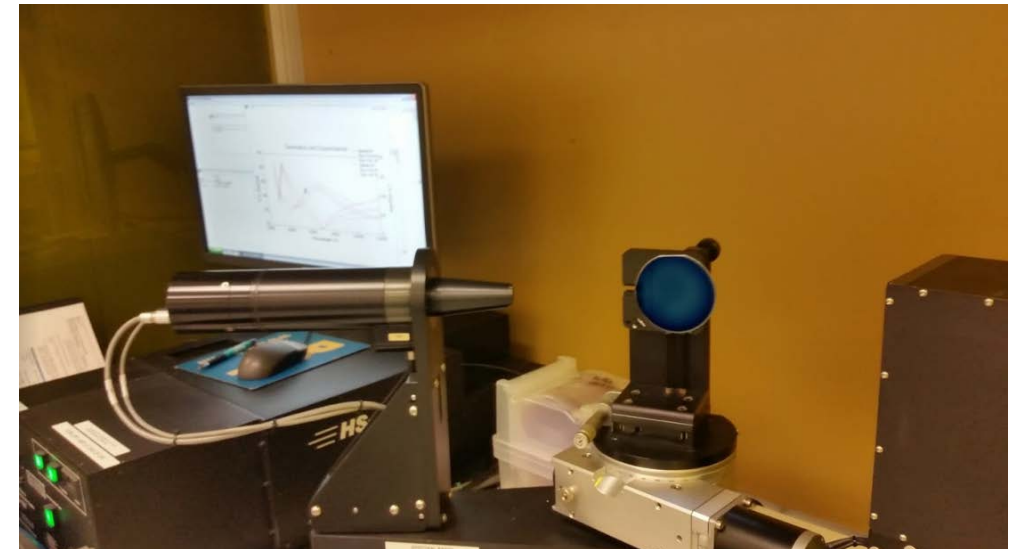
# Measuring Index of Refraction

The light dispersion through each film material was investigated and experimentally measured using ellipsometry techniques. Each measured film was compared back to the bulk refractive properties found at RefractiveIndex.info.

Light Dispersion in ARC



WVASE Setup





# Measuring Film Thicknesses

## ❖ P2 Tencor Profilometer

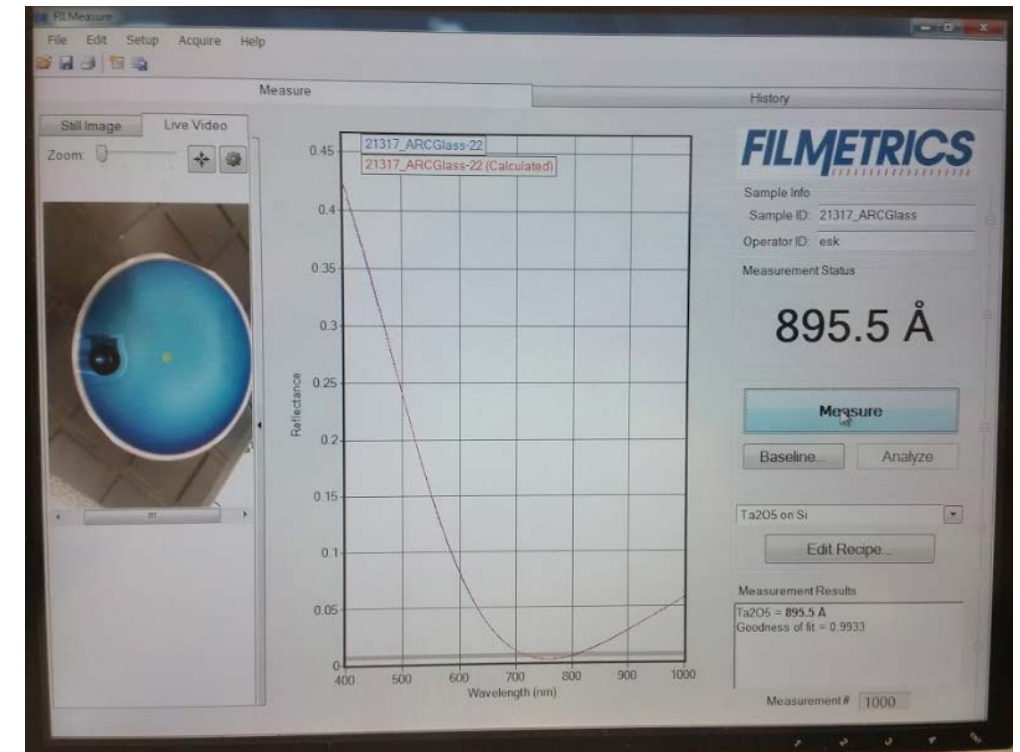
- ❖ Glass monitor slides bisected with kapton tape
- ❖ Step heights measured from glass to substrate

## ❖ WVASE

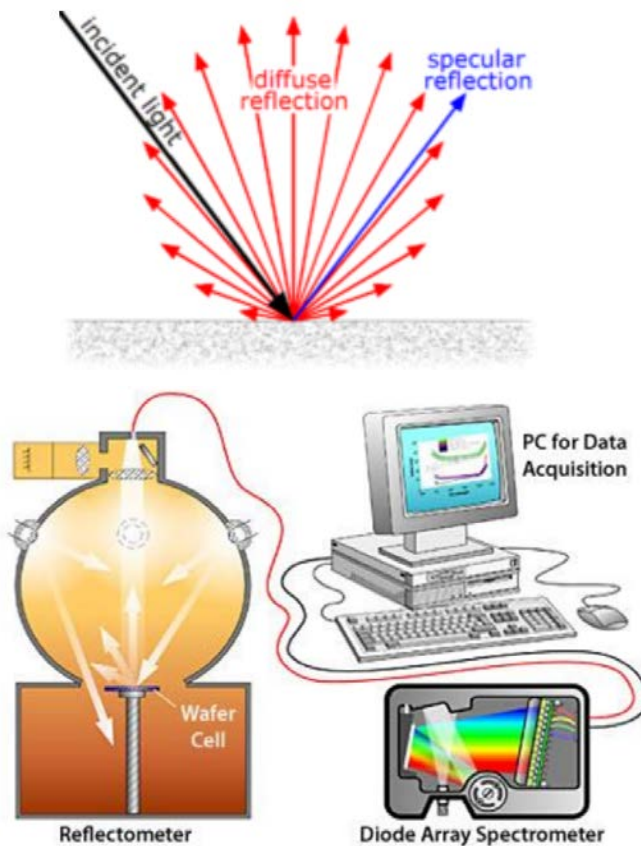
- ❖ Cauchy model was used for each material
- ❖ Both index of refraction and thickness can be measured
- ❖ Profilometer results used as baseline thicknesses

## ❖ Filmetrics Reflectometer

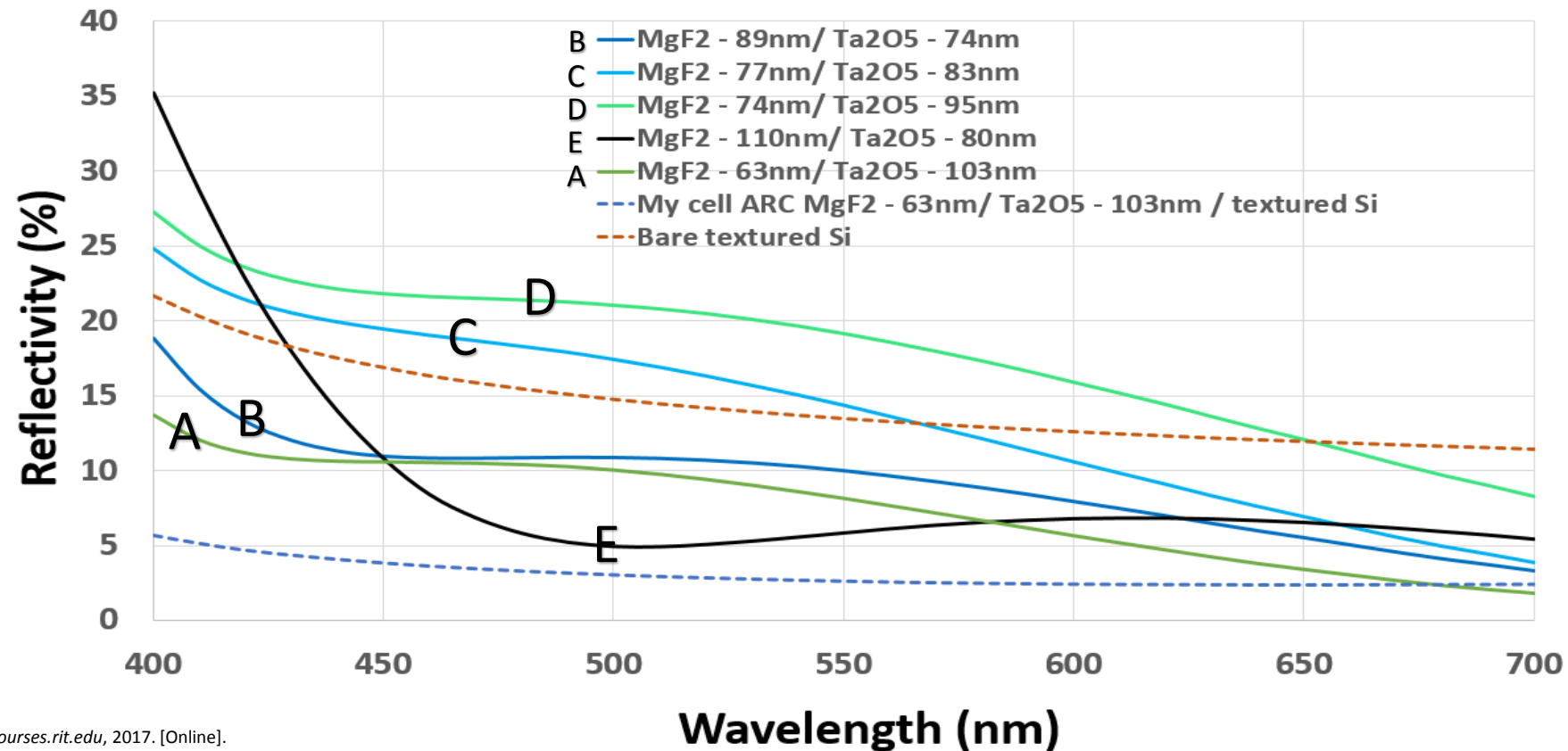
- ❖ Used to originally measure  $\text{MgF}_2$  on monitor slides
- ❖ Imported  $\text{Ta}_2\text{O}_5$  index data from WVASE
- ❖ Much faster to use than both the WVASE and P2 Tencor



# Reflectivity Measurements at the University of Rochester



## Experimental Diffuse Field Reflectivity



[5]"Lecture 23: PV Measurements", Photovoltaic Science & Engineering, S. Kurinec, *Mycourses.rit.edu*, 2017. [Online]. Available: <https://mycourses.rit.edu/d2l/le/content/631740/viewContent/4488407/View>. [Accessed: 04- May- 2017]

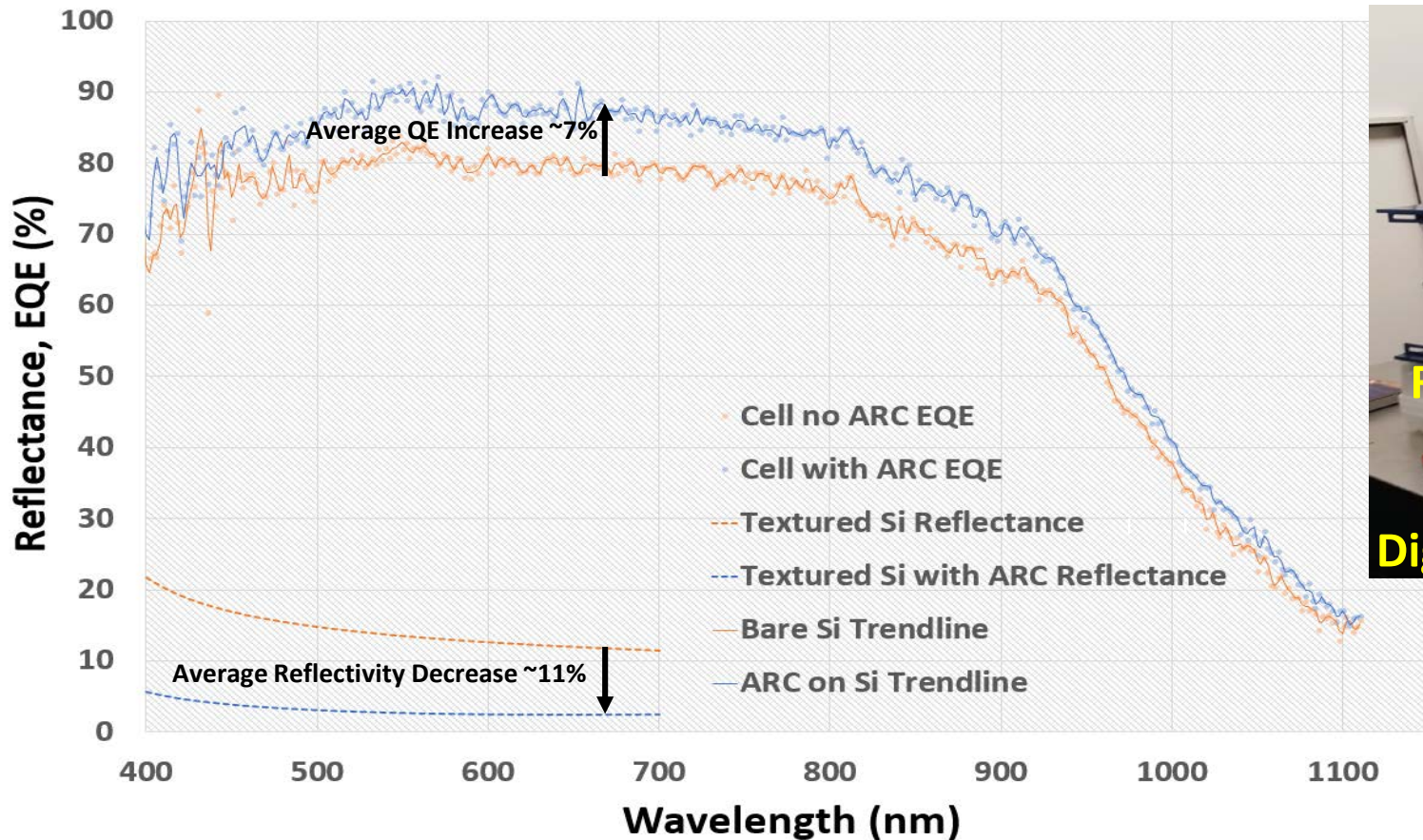
# Simulated vs Experimental Average Reflectance

Sample ID (MgF <sub>2</sub> -Ta <sub>2</sub> O <sub>5</sub> )	Simulated R <sub>avg</sub> (%)	Simulated with 6nm Interfacial Oxide R <sub>avg</sub> (%)	Experimental R <sub>avg</sub> (%)
<b>A</b> (103nm-63nm)	5.4776	5.9951	7.2
<b>B</b> (89nm-74nm)	6.7757	8.9558	8.9
<b>C</b> (77nm-83nm)	10.4181	13.392	13.2
<b>D</b> (74nm-95nm)	15.0234	17.6412	17.4
<b>E</b> (110nm-80nm)	6.4863	8.1601	8.1
<b>Textured Si cell no ARC</b>	-	-	14.0
<b>Textured Si cell with ARC 'A'</b>	-	-	2.9

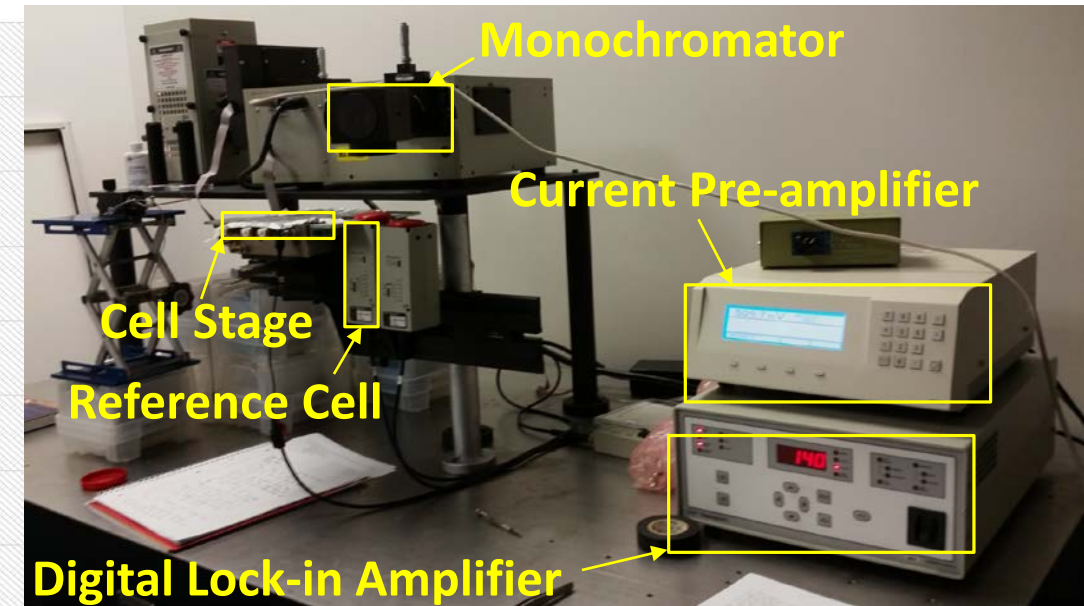
- Wafer samples for films **A** - **E** had a ~6nm thick native silicon oxide layer.
- Textured samples were chemically etched prior to depositing ARC.

# Solar Cell Quantum Efficiency Measurements

## Experimental Bi-layer ARC on c-Si Solar Cell



## QE Experimental Setup



# Conclusions and Future Work

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- The bi-layer ARC design that resulted in the lowest average reflectivity under AM0 spectral irradiance was determined to be 105 nm of  $\text{MgF}_2$  on top of 70 nm of  $\text{Ta}_2\text{O}_5$  when mathematically modeled.
- Diffuse reflectance measurements of the bilayer film stacks followed the same trend as the proposed model for a variety of thickness combinations.
- $\text{MgF}_2$ - $\text{Ta}_2\text{O}_5$  bi-layer ARC resulted in an average reflectivity decrease by 11% and increased the quantum efficiency by 7% in a commercial c-Si solar cell for wavelengths ranging from 400 nm to 700 nm.

## Future Work

- Utilize e-beam evaporation and deposit on dynamic substrates
- Test ARC on III-V solar cells, and test designs for AM1.5 applications
- Integrate deposition process into existing cell fabrication at RIT
- Incorporate surface roughness into MATLAB model



# Acknowledgements

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- University of Rochester
- NanoPower Research Laboratory

...AND THANKS TO ALL WHO ATTENDED!

# References

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- [1] Guenther, Robert D. *Modern Optics*. 1st ed. New York, Chichester, Brisbane, Toronto, Singapore: JOHN WILEY & SONS, 1990. Print.
- [2] "Quantum Efficiency | Pveducation". *Pveducation.org*. N.p., 2017. Web. 23 Apr. 2017.
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